

INFORMATION DISCLOSURE CITATION IN AN APPLICATION				ATTY. DOCKET NO. 055071-0310		SERIAL NO. 10/705,234			
				APPLICANT Armin LIEBCHEN					
(PTO-1449)				FILING DATE November 12, 2003		GROUP 2851			
				U.S. PATENT DOCUMENTS					
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ² (if known)		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document		Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
<i>DL</i>			5,969,441	10/19/1999	Loopstra et al.				
<i>ER</i>		US	6,046,792	04/04/2000	Van Der Werf et al.				
<i>DL</i>		US	6,563,566 B2	05/13/2003	Rosenbluth et al.				
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FOREIGN PATENT DOCUMENTS									
EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes-Number & -Kind Codes (if known)		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document		Pages, Columns, Lines Where Relevant Figures Appear	Translation Yes No	
<i>PK</i>		WO 98/40791		09/17/1998	Konin Klijke Philips Electronics N.V.				
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.							
EXAMINER <i>P. L. B. K.</i>					DATE CONSIDERED <i>9/13/05</i>				

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EXAMINER'S INITIALS	CITE NO.	Document Number <small>Number-Kind Code2 (if known)</small>	Publication Date <small>MM-DD-YYYY</small>	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
<i>PK</i> ↓ <i>PK</i>		US 5,880,588	10-21-1997	Gortych et al.			
		US 5,300,788	04-05-1994	Brunner et al.			
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EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document <small>Country Codes - Number + Kind Codes (if known)</small>	Publication Date <small>MM-DD-YYYY</small>	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation <div style="display: flex; justify-content: space-between;">YesNo</div>	
<i>PK</i>		JP 2000-232057A				X	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)			
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	
<i>PK</i>		BURN J. LIN, "The Exposure-Defocus Forest," Jpn. J. Appl. Phys. Vol. 33 (1994) pp 6756-6764	
↓		M. DUSA et al., "Study of mask aerial images to predict CD proximity and line end shortening of resist patterns," Proc. of SPIE Vol. 4349 (2001), pp. 148-159	
↓		B.P. MATHUR et al., "Quantitative Evaluation of Shape of Image on Photoresist of Square Apertures," IEEE Transactions of Electron Devices, Vol. 35, No. 3 (March 1988), pp. 294-297	
↓		CHRISTOPHER J. PROGLER et al., "Merit functions for lithographic lens design," J. Vac. Sci. Technol. B 14(6), (Nov/Dec 1996), pp. 3714-3718	
<i>PK</i>		NISHRIN KACHWALA et al., "Imaging contrast improvement for 160 nm line features using sub resolution assist features with binary, 6% ternary attenuated phase shift mask with process turned resist," SPIE Vol. 3679 (1999), pp. 55-67	

EXAMINER 	DATE CONSIDERED <div style="font-size: 1.5em; font-family: cursive;">9/13/05</div>
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.